

# Ralchenko Viktor G. Course Schedule

## WEDNESDAY

10:15 – 13:30	■ SEM	Plasma Cvd of Thin-film Structures (2018-02-07 – 2018-04-11)	👥 M16-303	📍 FIAN
13:35 – 15:15	■ LEC	Plasma Cvd of Thin-film Structures (2018-02-07 – 2018-02-21)	👥 M16-303	📍 FIAN